

**Amendments to the Abstract:**

Pursuant to Rule 1.72, the attached abstract includes the changes to the abstract as indicted below.

**Abstract**

A substrate is set on a susceptor installed in a reactor and arranged horizontally. ~~Then, a~~ A cooling jacket is provided at ~~the opposite~~ a portion of the inner wall of the reactor that is opposite to the substrate. By flowing a given cooling medium through the cooling jacket with a pump connected to the jacket, at least the opposite portion of the inner wall is cooled down, ~~to inhibit which inhibits~~ the reaction between raw material gases introduced into the reactor. As a result, in fabricating a III-V nitride film, the film growth rate is developed and the crystal quality is developed.

Attachment: Replacement Sheet - Abstract

- 14 -

#### Abstract

A substrate is set on a susceptor installed in a reactor and arranged horizontally. A cooling jacket is provided at a portion of the inner wall of the reactor that is opposite to the substrate. By flowing a given cooling medium through the cooling jacket with a pump connected to the jacket, at least the opposite portion of the inner wall is cooled down, which inhibits the reaction between raw material gases introduced into the reactor. As a result, in fabricating a III-V nitride film, the film growth rate is developed and the crystal quality is developed.